



52. A process as in claim 51, where the material is loaded electrochemically.

53. A process as in claim 51 wherein the frequency of said vibration is followed by the material producing interference with an optical beam.

54. A process as in claim 51 wherein said material is a member of the group consisting of palladium and palladium alloys.

55. A process as in claim 51 wherein said second material is a member of the group consisting of deuterium or deuterons.

56. A process as in claim 51 wherein said means to drive said vibration is provided by additional coupling also to a longitudinal mass capable of providing restoring force along its length,

57. A process as in claim 51 wherein said means to drive said vibration comprises coupling said material to a second mass located external to said material.

58. A process as in claim 57 wherein said second mass is capable of having at least one vibrational frequency.

59. A process as in claim 57 wherein said second mass is driven by an electromechanical device .

60. An apparatus to monitor the loading of a material by a second material which includes in combination:

means to load said second material,

means to enable mechanical vibrations of said material by mechanically coupling said material,

means to drive said vibrations,

means to detect the frequency of said vibrations.

61. An apparatus as in claim 60 wherein said material is a member of the group consisting of palladium and palladium alloys.

62. An apparatus as in claim 60 wherein said second material is a member of the group consisting of deuterium or deuterons.

63. An apparatus as in claim 60 wherein said means to load said second material in the material is electrochemical.